

# Interlude: Vacuum Technology in a Nutshell



Topics:

Chamber: materials, seals

Pump: speed, pressure range

Pipes, valves: conductance, material

Component missing from photo?

Pressure has one of the largest dynamic ranges of any measured lab quantity. It might also have the largest variety of units.

SI:  $1 \text{ Pa} = 1 \text{ N/m}^2$

$1 \text{ atm} = 760 \text{ torr} = 101,325 \text{ Pa}$

$1 \text{ bar} = 10^5 \text{ Pa}$       $1.33 \text{ mbar} = 1 \text{ torr}$

# Vacuum Technology, Gas Properties

The total pressure can be (easily) measured but the microscopic makeup and behavior of the gas(es) are very important in vacuum systems. Partial pressures can be measured with a mass spectrometer: “residual gas analyzer” (RGA).

**Dry Air:** 78.08 % nitrogen, 20.94 % oxygen, 0.93% Ar, 0.03% CO<sub>2</sub> ...

**Humid Air:** estimate of partial pressure of H<sub>2</sub>O is 24 Torr \* (relative Humidity)  
( note it can be up to ~3% of the air and is temperature dependent )

Mean gas velocity: 
$$v = \left( \frac{8k_B T}{\pi m} \right)^{1/2} = \left( \frac{8RT}{\pi MM} \right)^{1/2} = \frac{2512 \text{ m/s}}{\sqrt{MM(\text{g/mol})}} \quad \text{at 298 K}$$

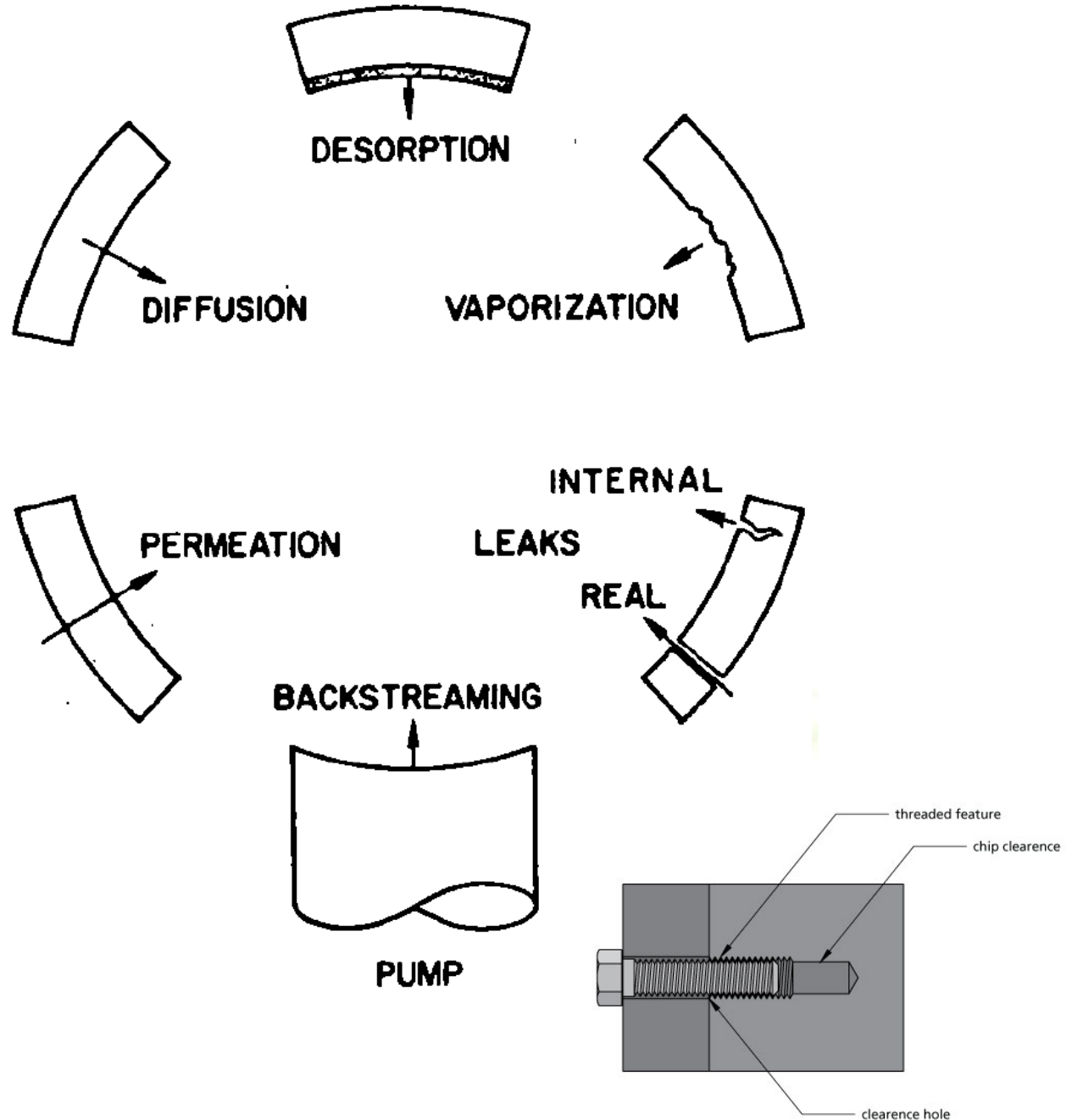
Effusion: 
$$\frac{v_1}{v_2} = \left( \frac{MM_2}{MM_1} \right)^{1/2}$$

Mean Free path: 
$$\lambda = \frac{1}{\sqrt{2} \pi d^2 \rho_n} = \frac{6.6 \text{ mm Pa}}{P} :$$

# Vacuum Technology, Gas Sources

Summary Figure 4.1 in  
O' Hanlon, 2<sup>nd</sup> Ed. & 3<sup>rd</sup> Ed.

Sources of residual gas after  
the bulk filling gas has been  
removed.



Most important residual gas  
of a system with no leaks  
varies with time ...

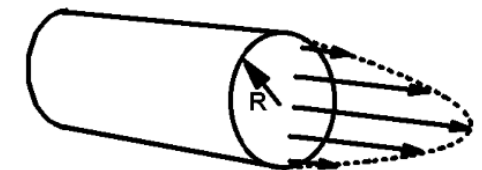
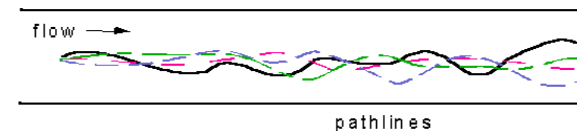
First H<sub>2</sub>O then ultimately H<sub>2</sub>

Two dimensionless numbers are used to characterize gas flow regimes:

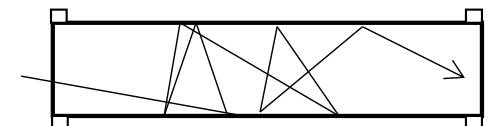
Knudsen's Number:  $Kn = \lambda / d$        $\lambda$  – mean free path,  $d$  – pipe diameter

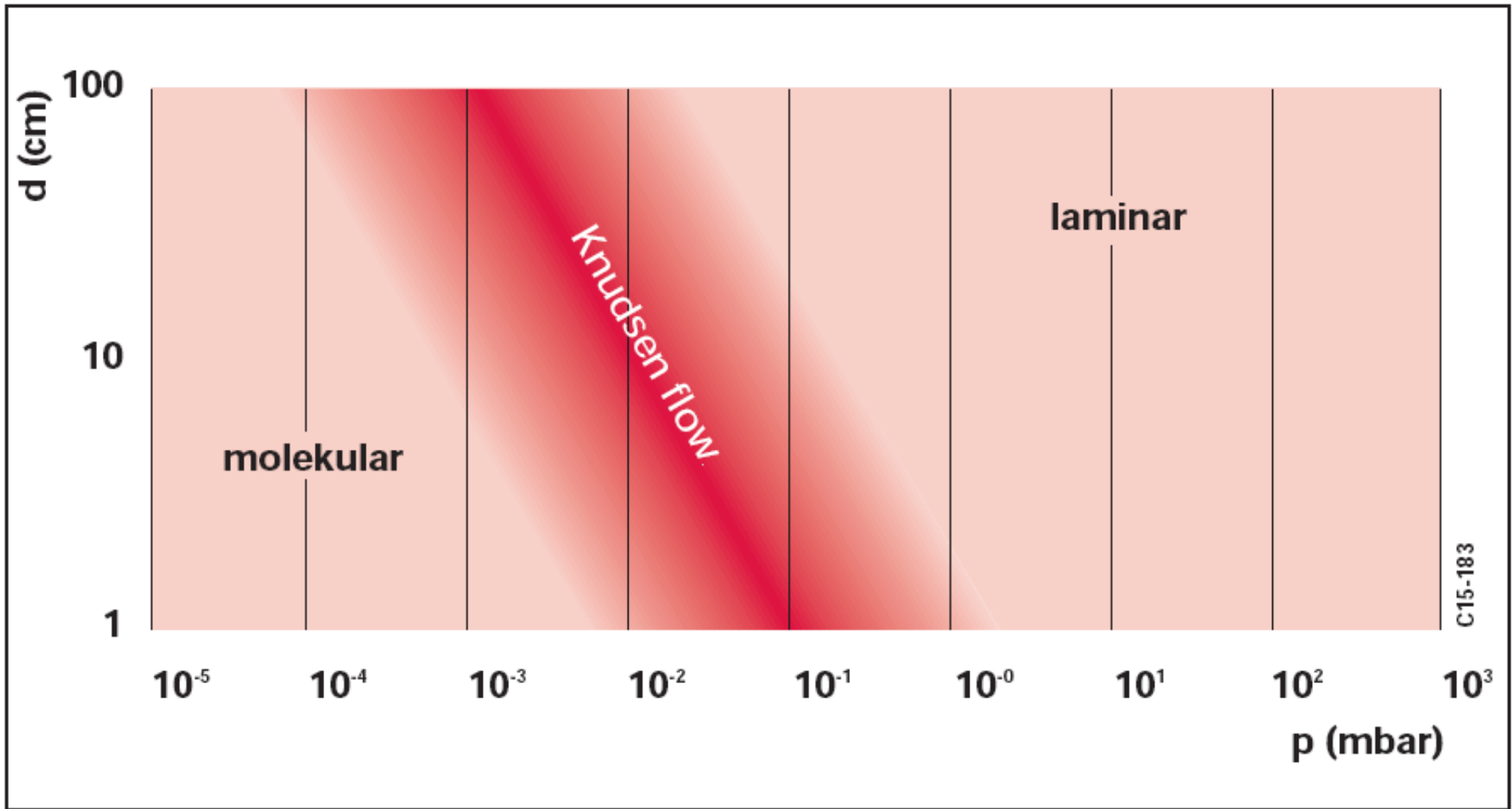
Reynold's Number:  $Re = U \rho d / \eta$      $U$  – stream velocity,  $\rho$  – density,  $\eta$  – viscosity

	Kn	Re
Turbulent	$\ll 0.01$	$> 2200$
Viscous Laminar	$< 0.01$	$< 1200$
Molecular	$> 1$	$< 1200$



visco8





From: Pfeiffer Vacuum, “[Working with Turbopumps](#)” on class website.  
See revised website by manufacturer:

<https://www.pfeiffer-vacuum.com/en/know-how/vacuum-generation/turbomolecular-pumps/>

Gas flow can be analyzed in terms of the volume of gas, at some pressure, that passes a plane in a fixed period of time:  $Q = d(PV)/dt$  where  $Q$  is called the “throughput” and has many sets of dimensions along the lines of torr-l/s .

All gases behave ideally at low pressure and nearly ideal under lab conditions.

$$Q = \frac{d(PV)}{dt} \quad PV = nRT \rightarrow Q = RT \frac{dn}{dt} \quad (\text{if isothermal})$$

Thus,  $Q$  also has units of energy/time = power (i.e., watts).

(A) When the system is in a steady state with a constant pressure:

$$Q = P \frac{dV}{dt} = P S \quad S \text{ is the } \textit{Speed} \text{ of the pump, e.g. liter/s}$$

(B) Whereas for continuous flow through a pipe with a pressure difference:

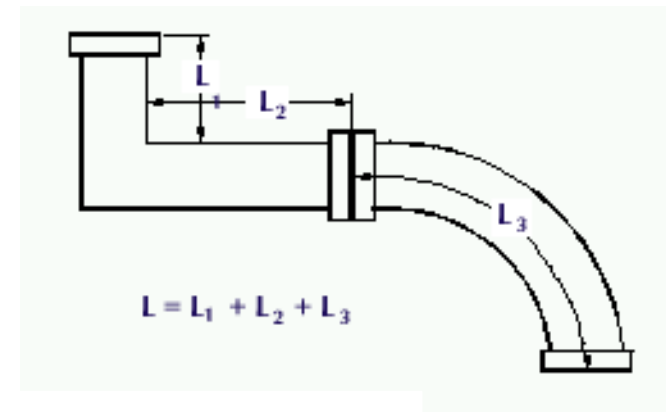
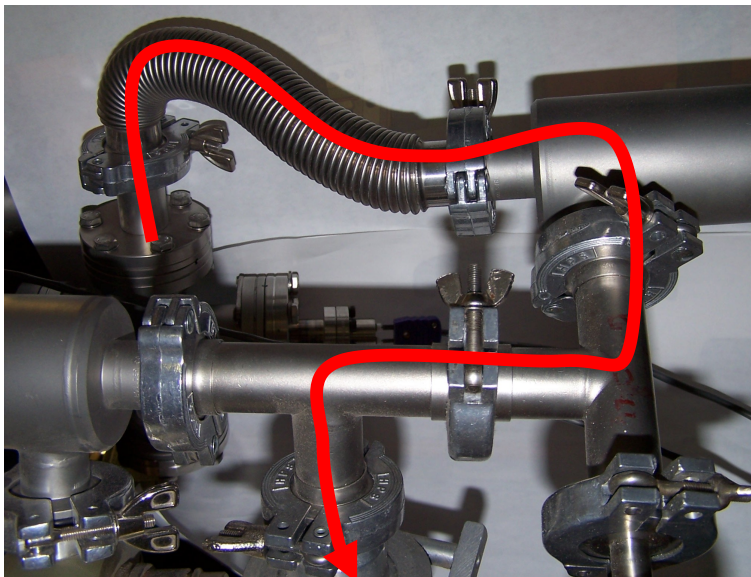
$$Q = C (P_2 - P_1) \quad C \text{ is the } \textit{Conductance} \text{ of the pipe, e.g. liter/s}$$

# Vacuum Technology, Gas Flow –3–

The so-called fundamental vacuum equation is  $PS = C \Delta P$ . The pump speed,  $S$ , is a function that depends on the design of the pump *and* the pressure. Similarly, the conductance,  $C$ , depends on the design of the plumbing, the pressure and the gas.

	Laminar	Molecular
Aperture	(complicated, called choked flow)	$A v / 4$
Long Pipe	$\frac{\pi d^4}{128 \eta l} \frac{P_1 + P_2}{2}$	$(\pi/12) v d^3 / l$

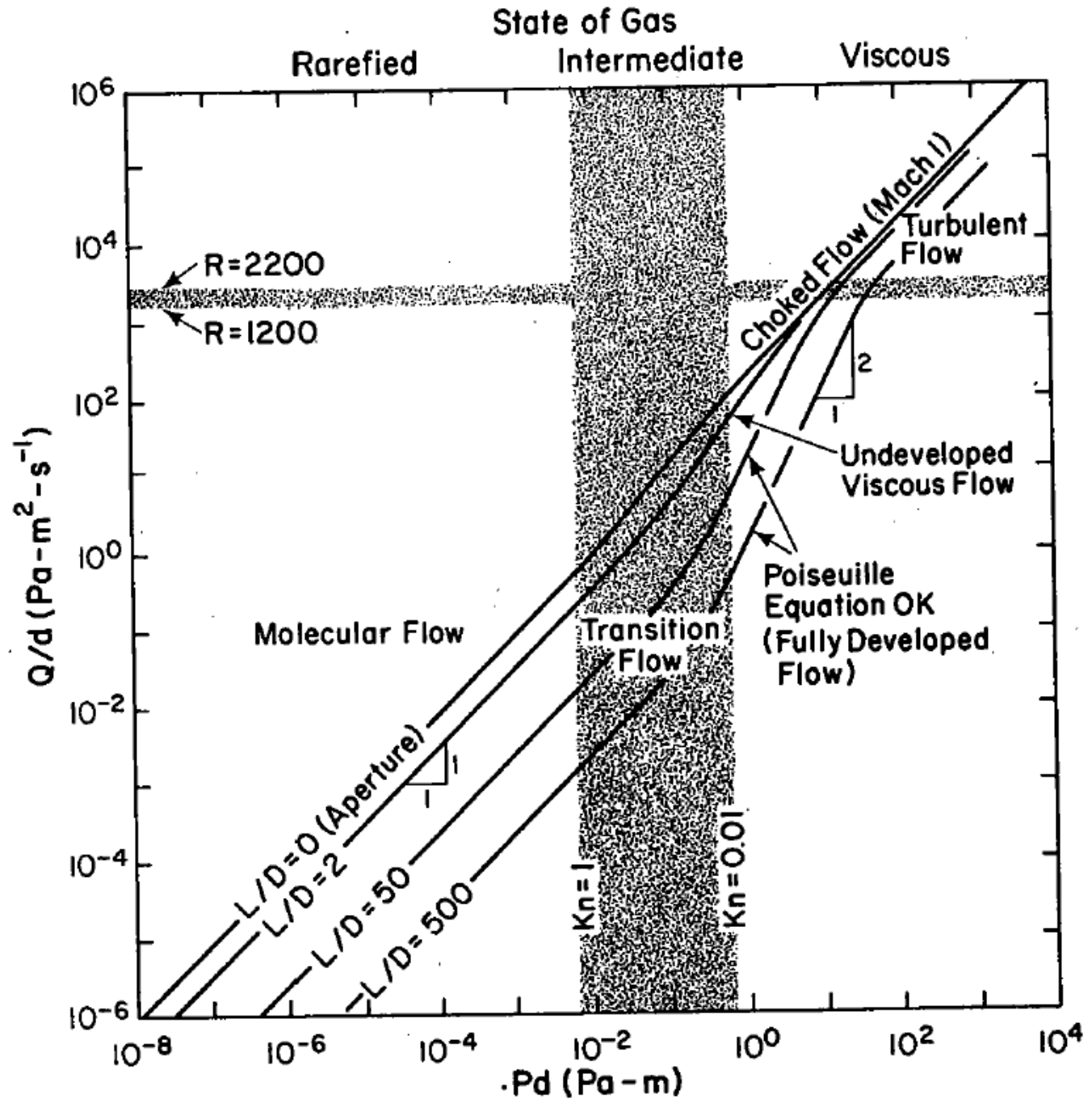
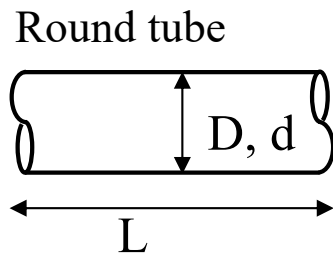
Conductances are combined in reciprocal:  $1/C_{\text{total}} = 1/C_1 + 1/C_2 + \dots$



## Flow Summary

Figure 3.17  
O' Hanlon, 2<sup>nd</sup> Ed.

Figure 3.18  
O' Hanlon, 3<sup>rd</sup> Ed.



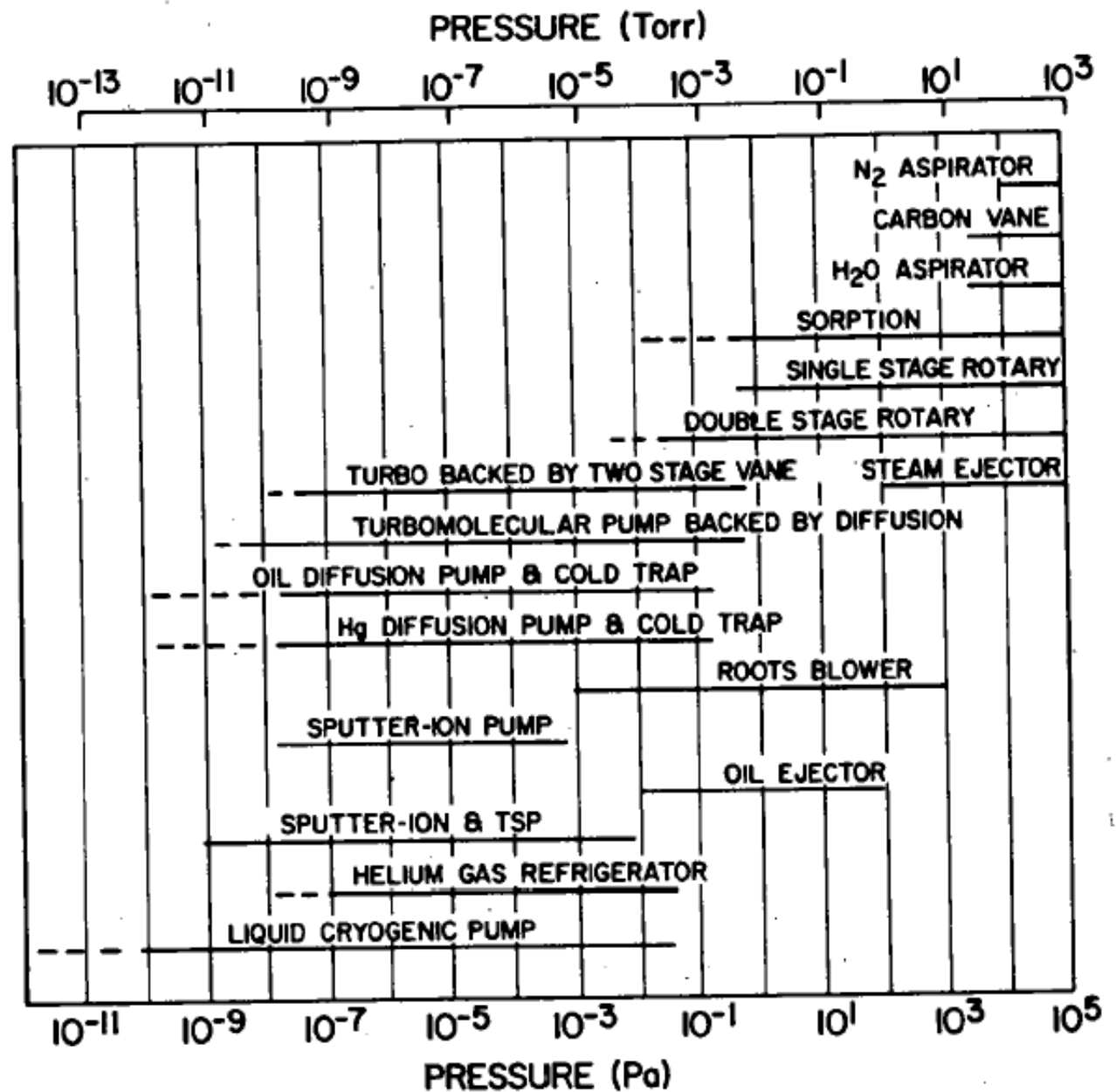


# Vacuum Technology, Production –1–

A huge variety of vacuum pumps have been developed over time that use various physical techniques to trap, and in a few cases move, the gas. In general, their usefulness is limited to certain pressure ranges.

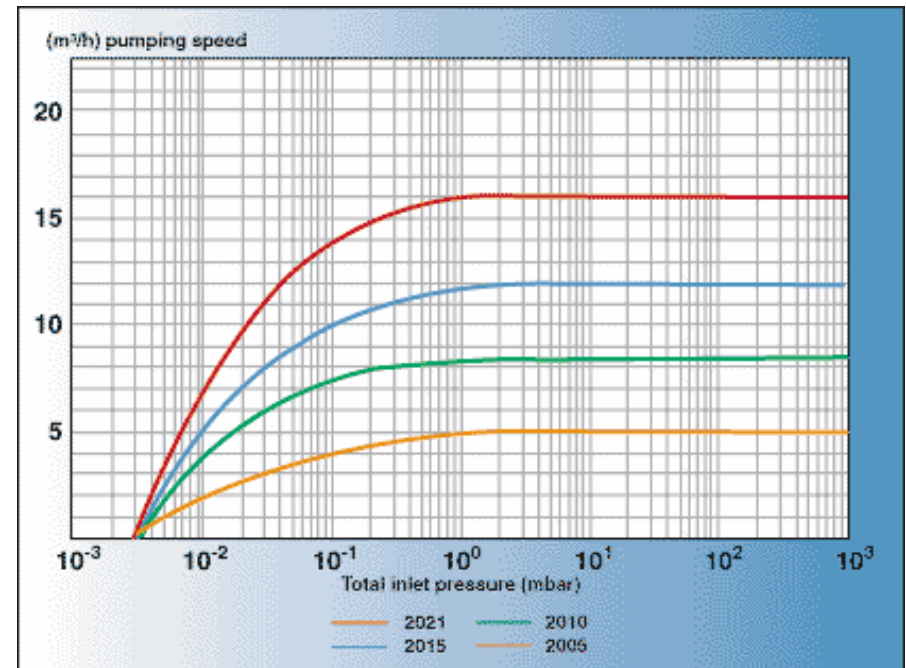
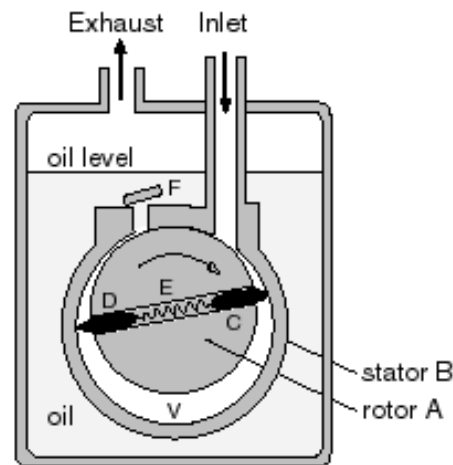
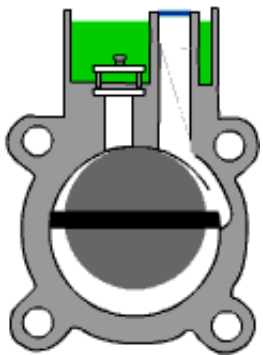
An important distinction among pumps: Is it sealed or does it have a path from inside to outside during operation?

Another distinction is: Are there moving parts or not?



**Mechanical pumps:** characterized by an eccentric rotor, vanes and stages

Oil-sealed



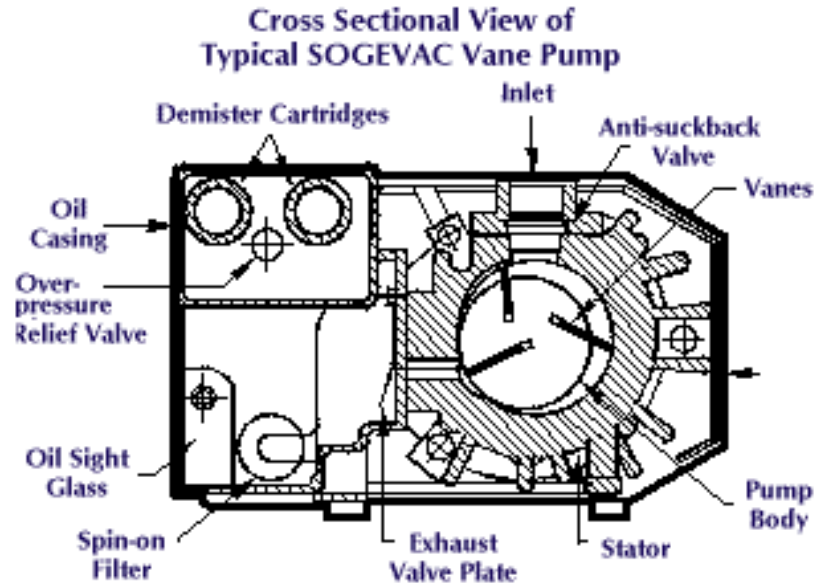
Alcatel Vane pump



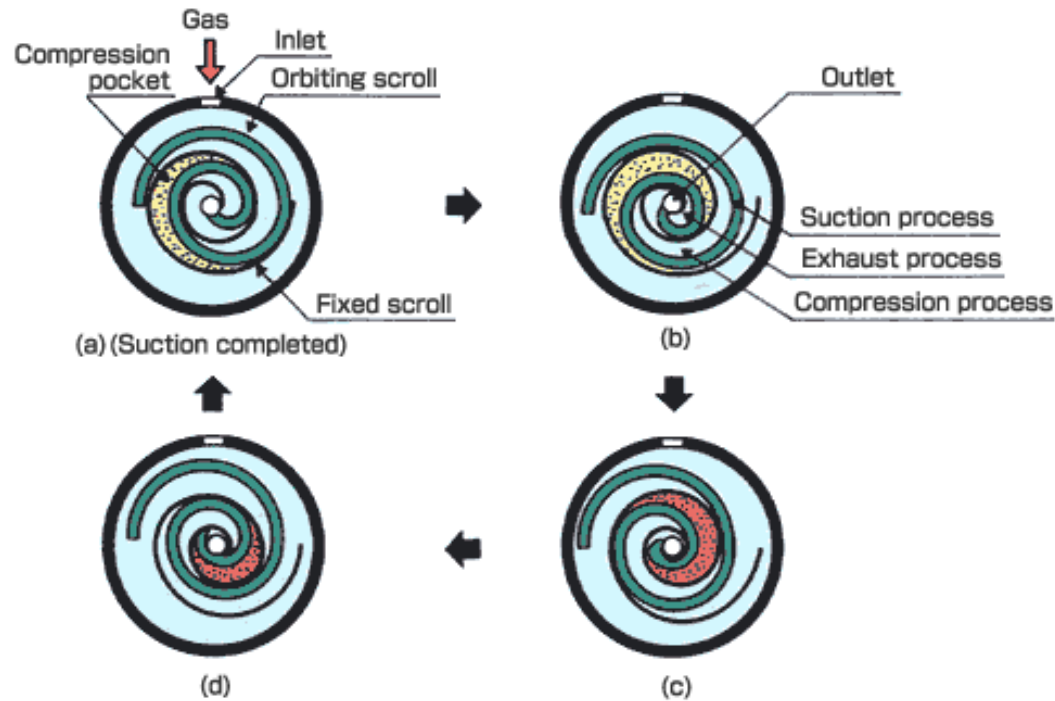
$$S = \frac{dV}{dt} \approx \frac{\Delta V}{\Delta t}$$

Mechanical pumps: oil free

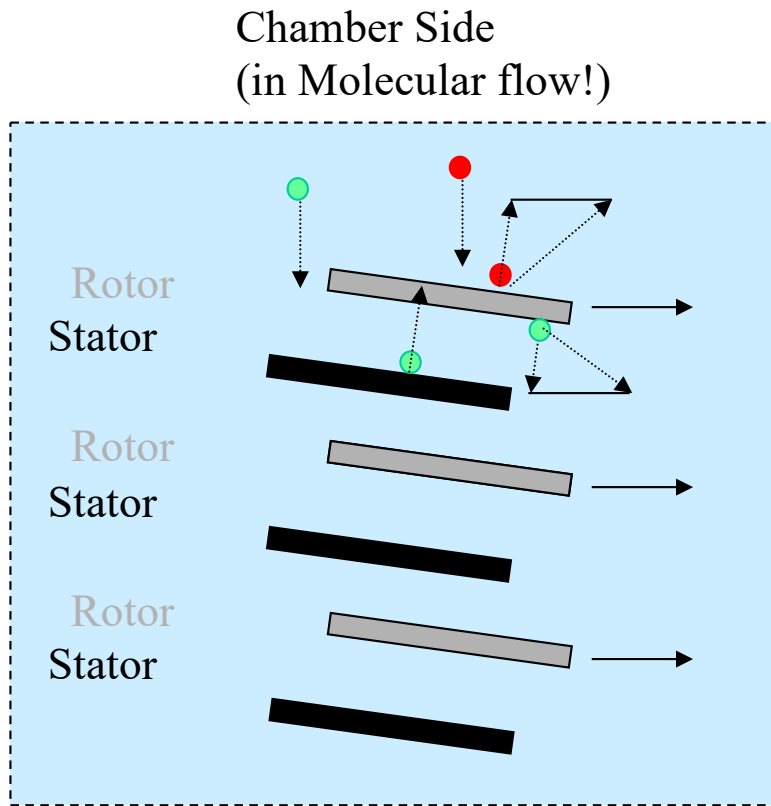
Dry Vane



Dry Scroll

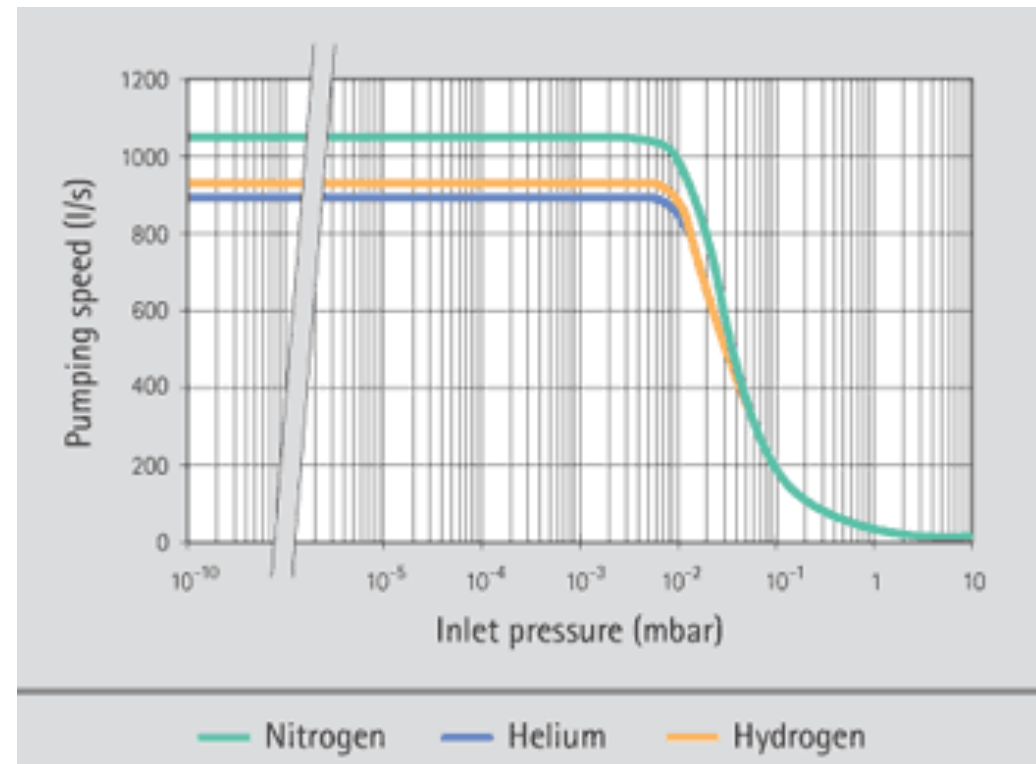


## High Vacuum pumps: TMP



Pump outlet Side

$$S_{\max} < C_{\text{aperture}} / 2$$



Varian Turbo-V 1001



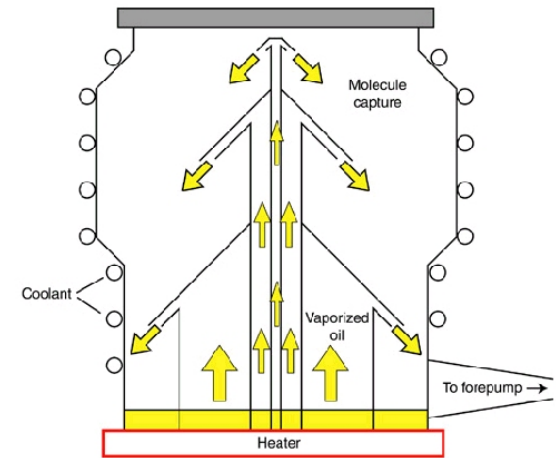
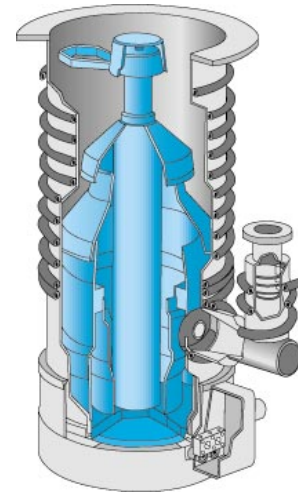
High flow



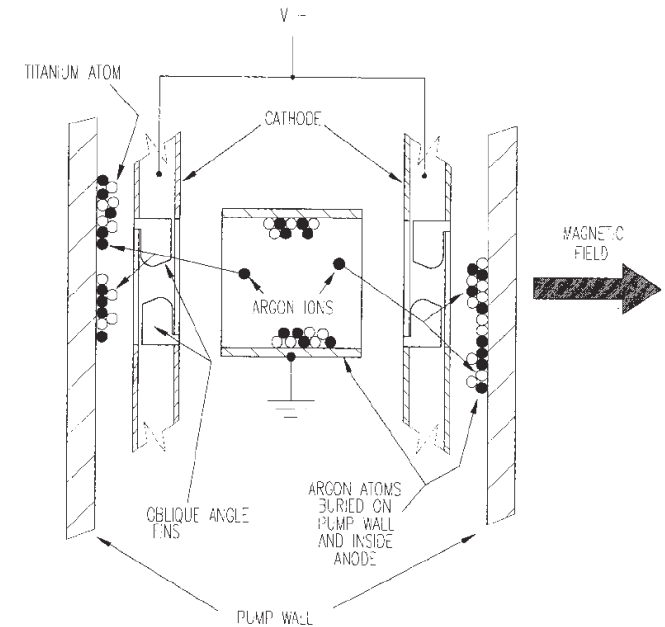
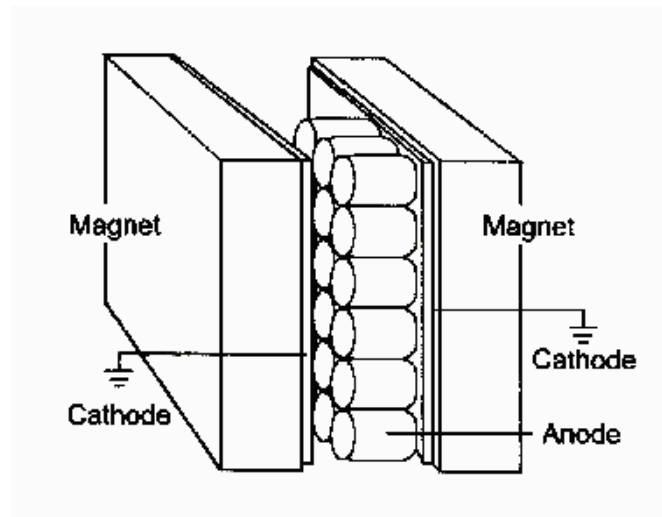
High Compression

## High Vacuum pumps: Diffusion pumps

Hot oil-filled, need cold traps  
Highest pumping speeds for He  
No real limit to size

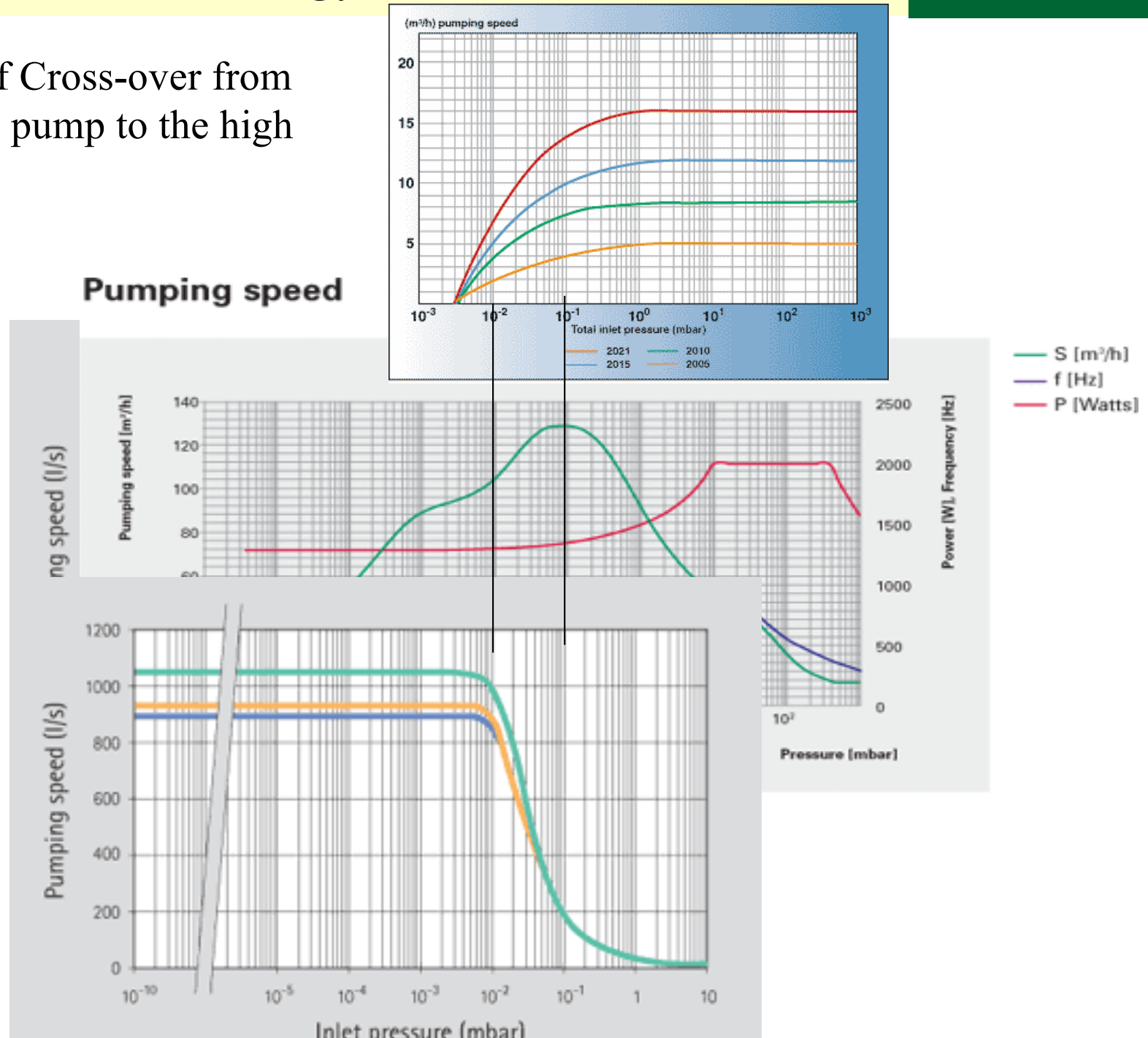


## High Vacuum pumps: Ion pumps – closed system



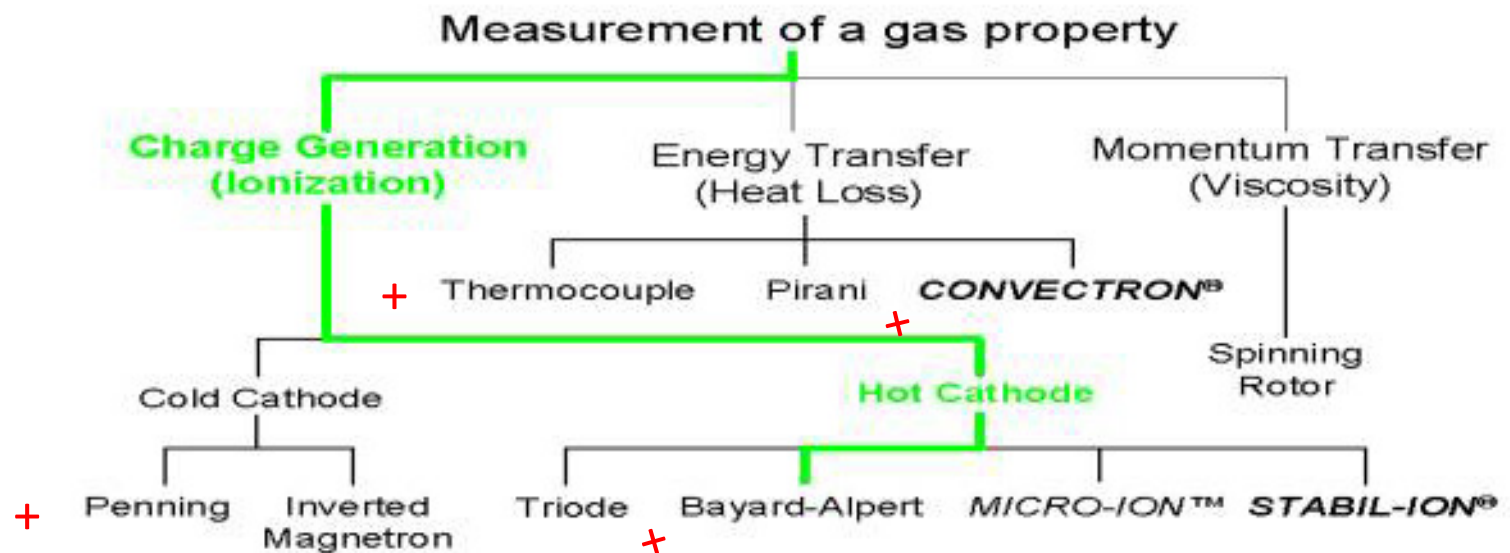
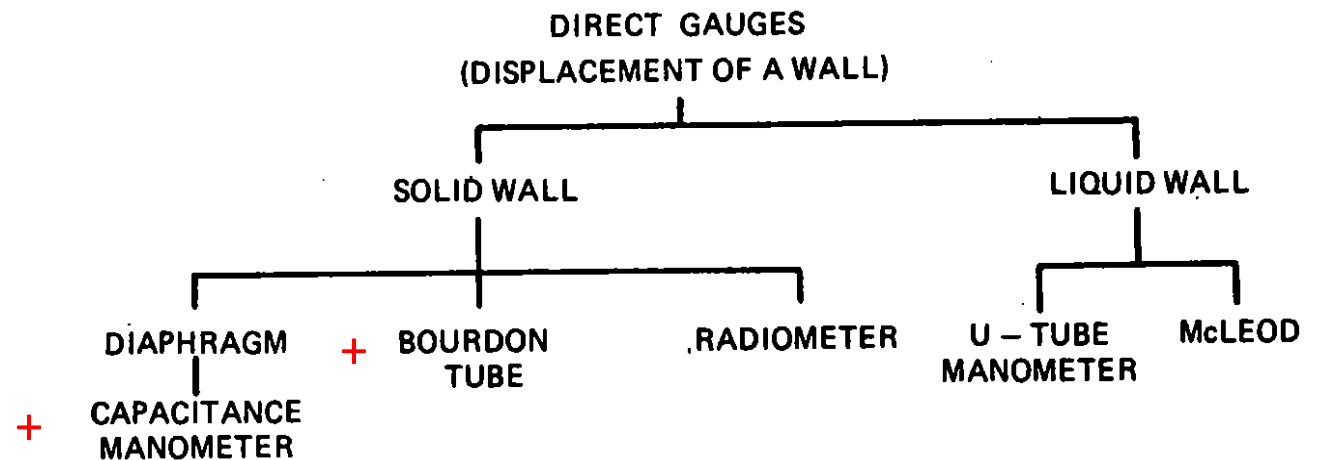
# Vacuum Technology, Production –5–

The problem of Cross-over from the mechanical pump to the high vacuum pump:



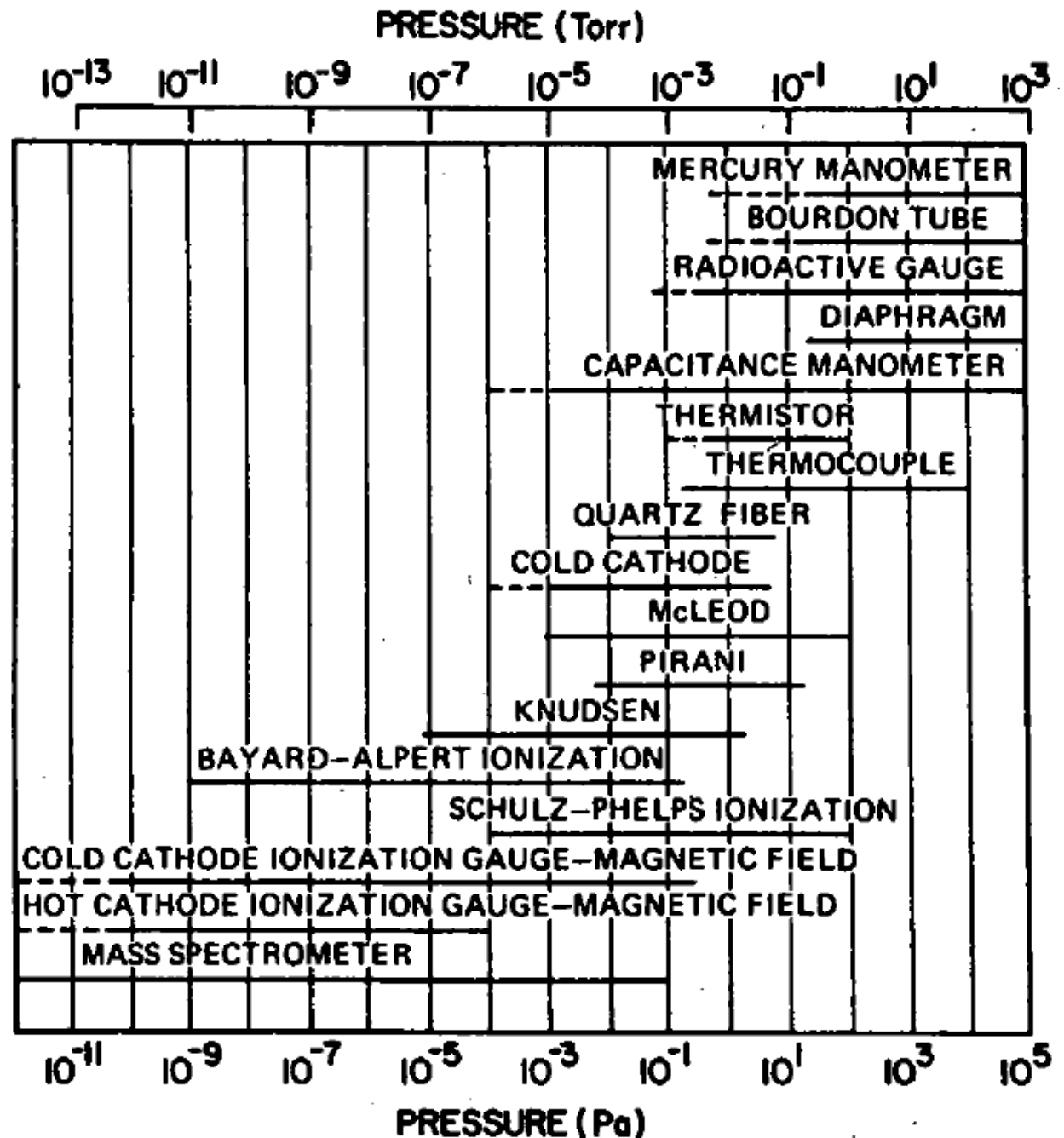
## Categorization of Vacuum Gauges

Figure 5.1  
O' Hanlon,  
2<sup>nd</sup> or 3<sup>rd</sup> Ed.



## Ranges of Vacuum Gauges

Figure 5.2  
O' Hanlon,  
2<sup>nd</sup> or 3<sup>rd</sup> Ed.



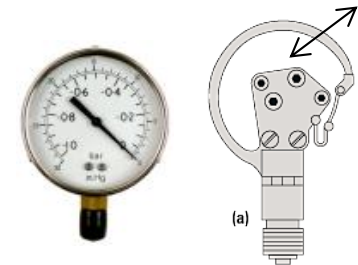
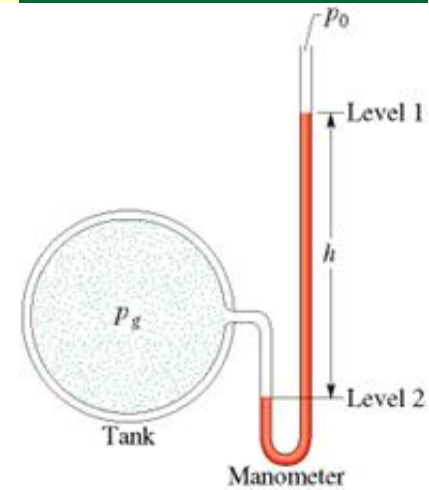


High pressure:

Mechanical or Moving wall

*Liquid wall* – classical manometer, key feature is the density of the liquid, low pressure limit is set by the vapor pressure of the liquid,  $p_0$ , and being able to read small differences in column heights.

*Solid wall* – key feature is stiffness of the metal wall (can be tuned to the pressure region), low pressure limit again due to detection of smallest physical motion. Recent devices use pizeoresistive chips.

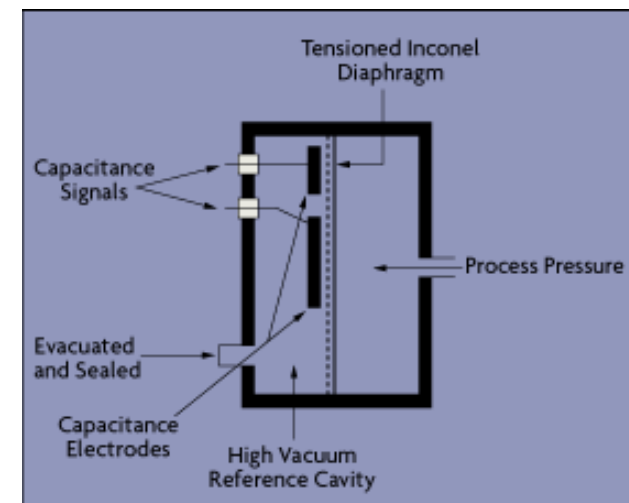
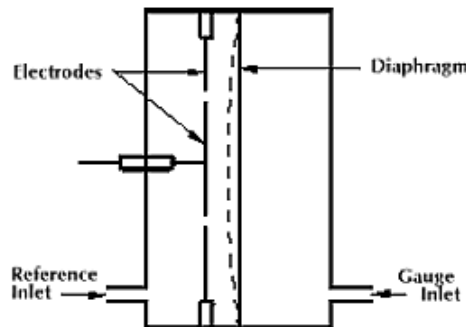


Bourdon tubes measure relative to external pressure connected to a mechanical gauge.

Capacitance manometers, Electronic readout, compatible with UHV

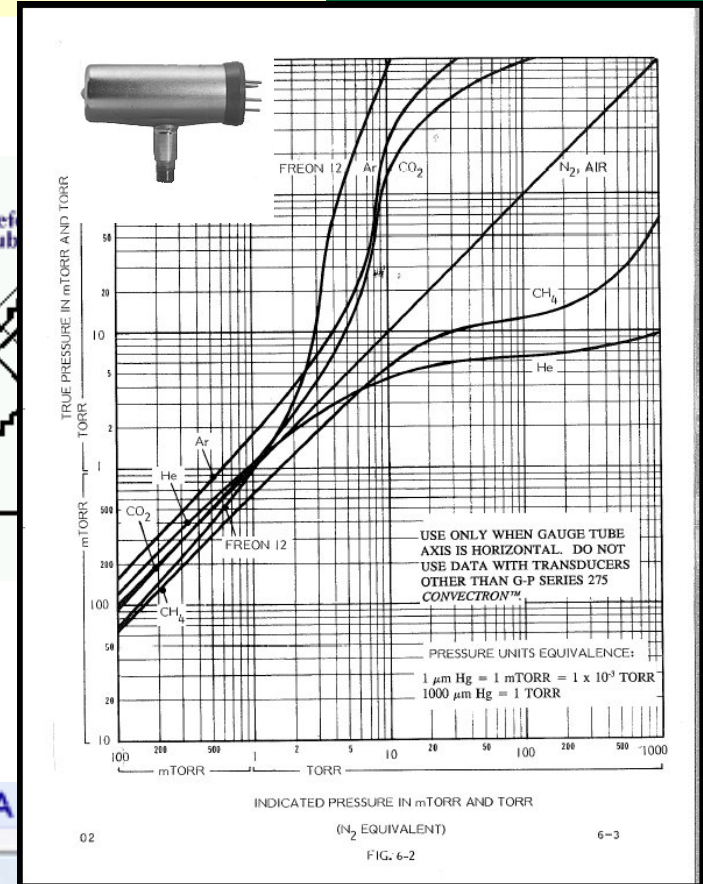
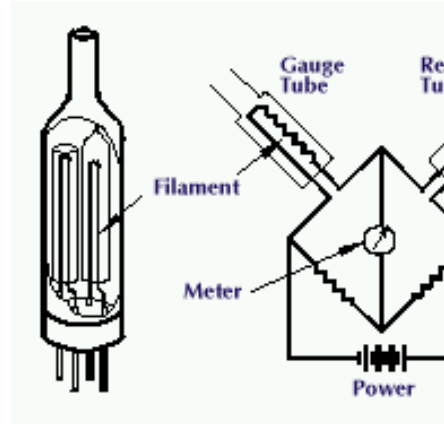


MKS device

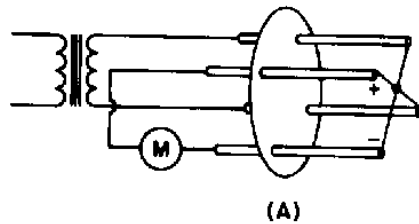


Medium pressure: measure heat transport

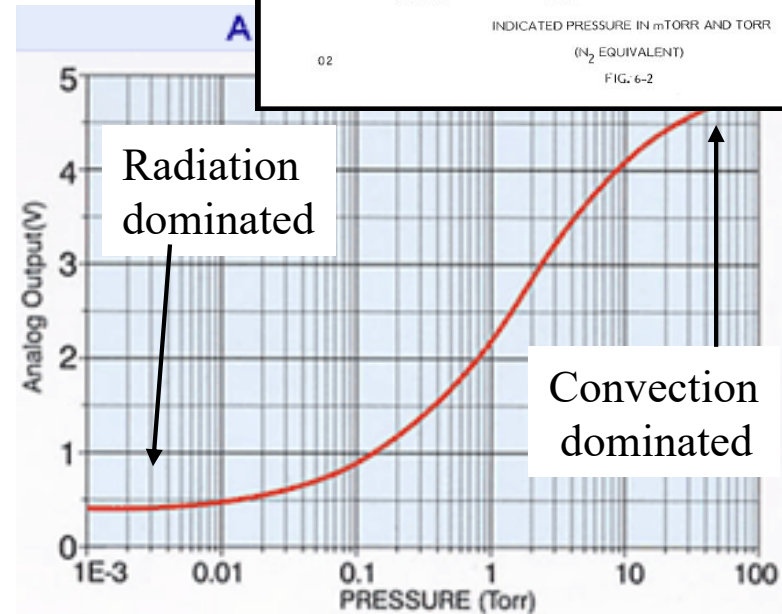
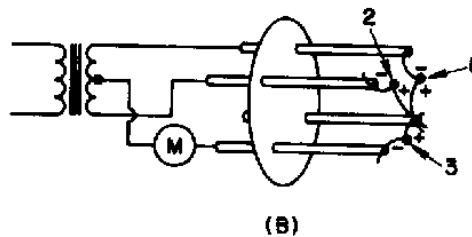
Pirani gauge – thermal transpiration



Thermocouple gauge – simple TC



or Compensated Hastings Gauge



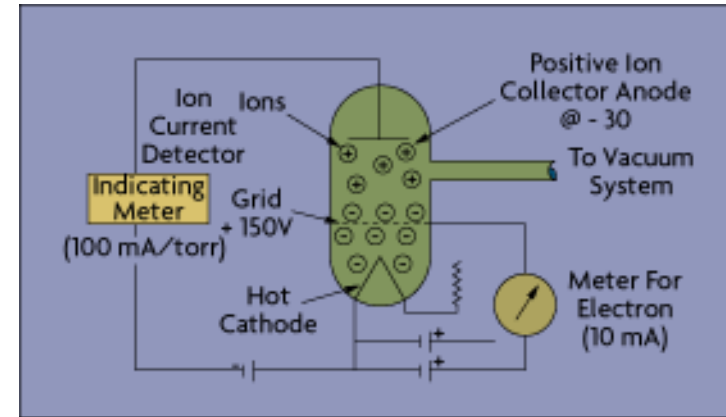
Low pressure: create & measure positive ion current and thus the  $\rho_n$  or number density of the gas (T dependent because  $n/V = P/RT$ ).

Hot filament gauge – hot cathode, Bayard-Alpert ...

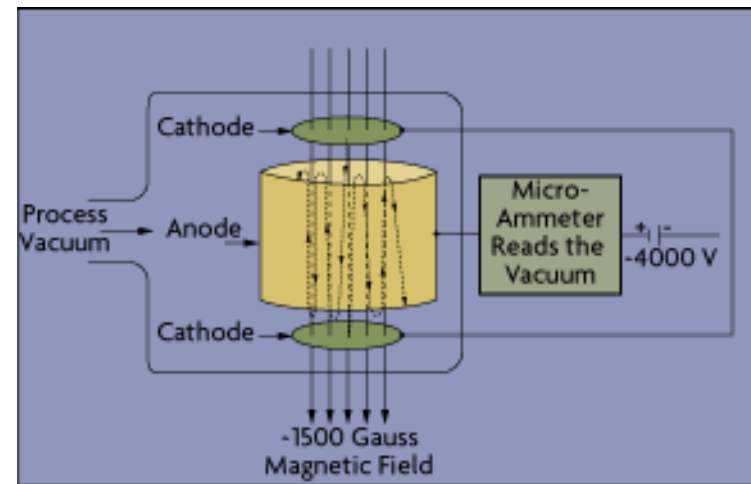


$$I^+ \propto s I^- P$$

$s \sim 1$  for  $N_2$ , 5 Acetone, 0.2 He



Cold filament gauge – cold cathode, Penning Gauge, inverted magnetron



# Gauge-ology, Now for an example

## Vacuum Technology

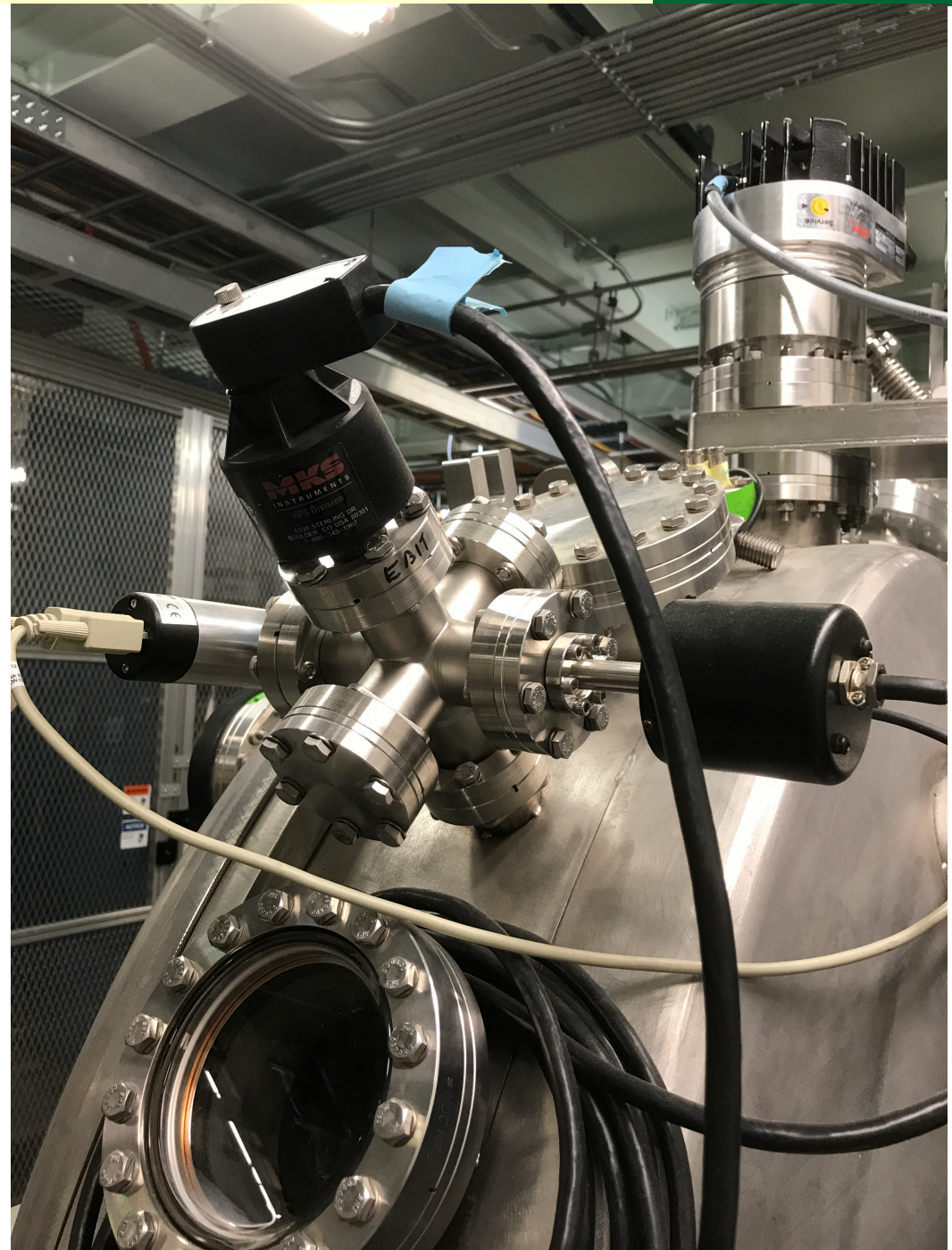
- Principles
- Gas Flow
- Pumps
- Gauges

## **Vacuum Technology**

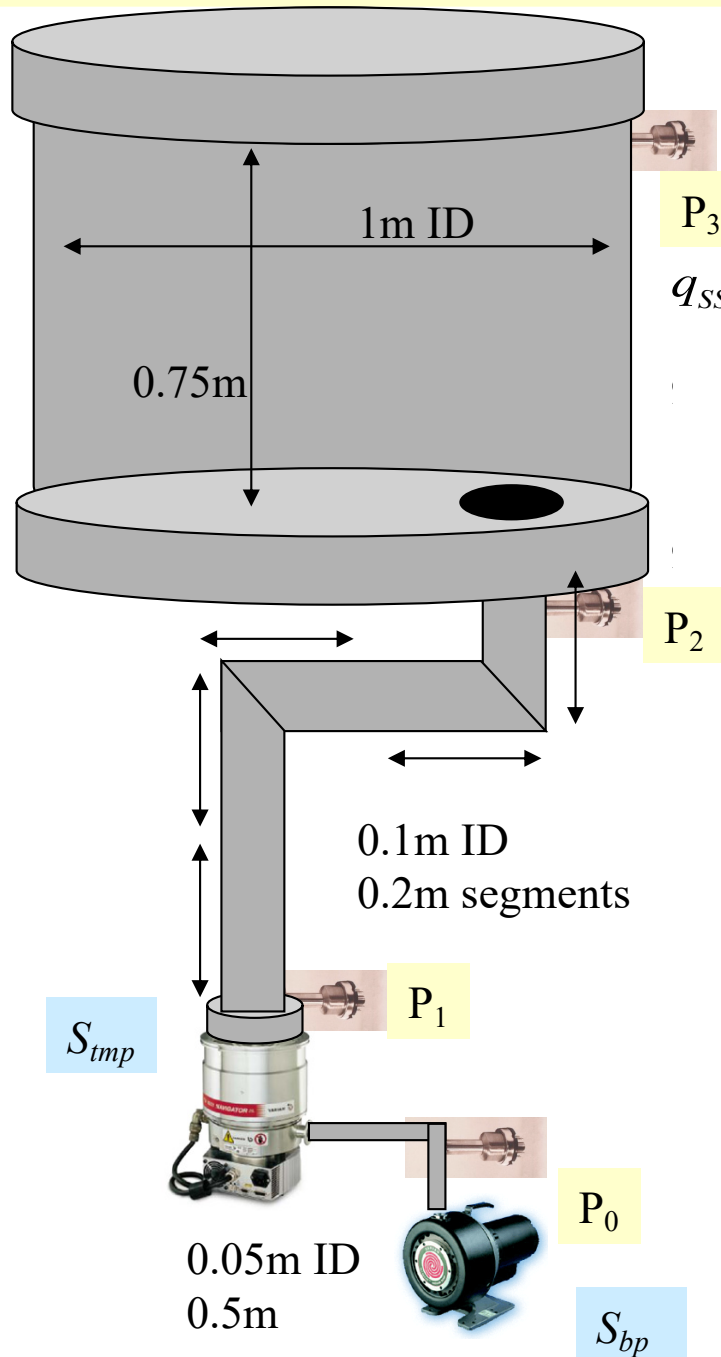
- Example System
- Calculation

## **General use of Statistical Distributions in Radiation Measurements**

- Fluctuations in Number
- distribution models
- Fluctuations in Time



# Vacuum Technology, Simple System –1–



**Complete system: Molecular Flow & no leaks!**

SS chamber,  $S_{tmp} = 300$  l/s, ( $S_{bp} = 200$  l/min)

P<sub>3</sub>

$$q_{SS} \sim 2 \times 10^{-5} t^{-1.3} \left( W / m^2 \right)$$

$$Q_{off-gas} = q_{SS} A_{Total}$$

P<sub>2</sub>

0.1m ID  
0.2m segments

P<sub>1</sub>

$S_{tmp}$

P<sub>0</sub>

0.05m ID  
0.5m

$S_{bp}$

# Vacuum Technology, Simple System –2a–

## Conductance in Molecular Flow

Best approach is to Monte Carlo the flow ...

Oatley Method to combine conductances

$$C = a C_{\text{aperture}}$$

=  $a Av/4$  where “a” is a transmission coefficient

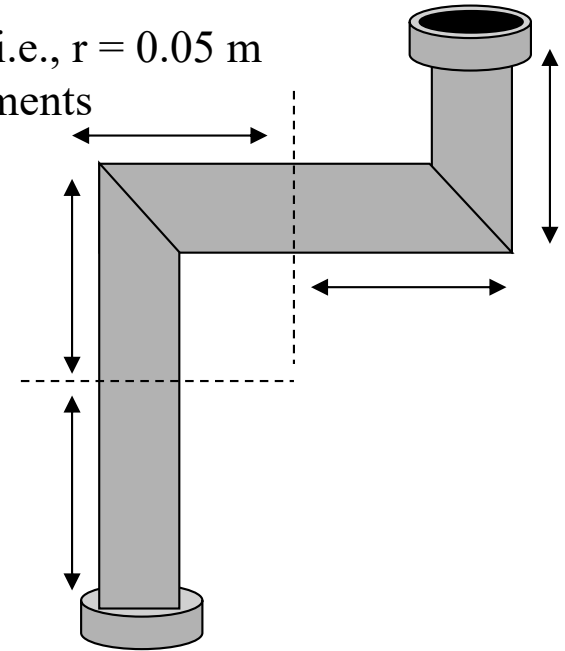
$$(1 - a) / a = (1 - a_1) / a_1 + (1 - a_2) / a_2 + (1 - a_3) / a_3 + \dots$$

Two elbows with  $L=0.2$  m arms,  $L/r=4$ ,  $a_1 = a_2 \sim 0.25$

One pipe with  $L=0.2$  m,  $L/r=4$ ,  $a_3 \sim 0.35$

0.1m ID, i.e.,  $r = 0.05$  m

0.2m segments



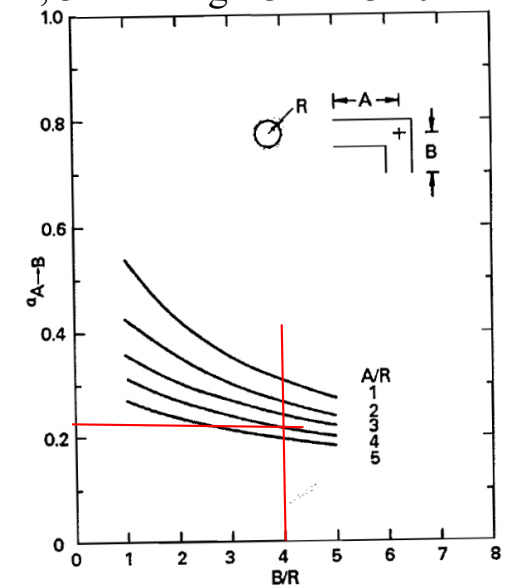
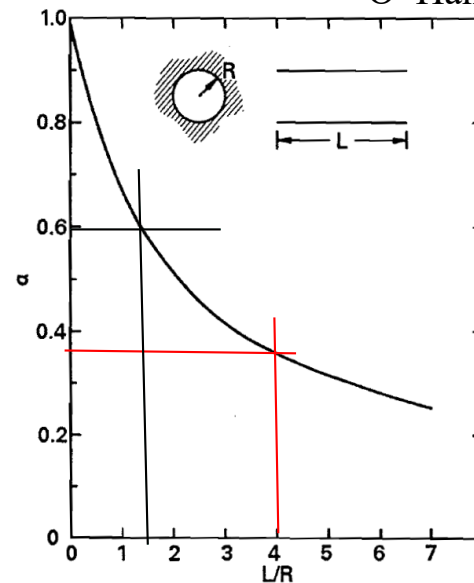
$$(1 - a) / a = 0.75/0.25 + 0.75/0.25 + 0.65/0.35 = 7.86$$

$$a = 0.113$$

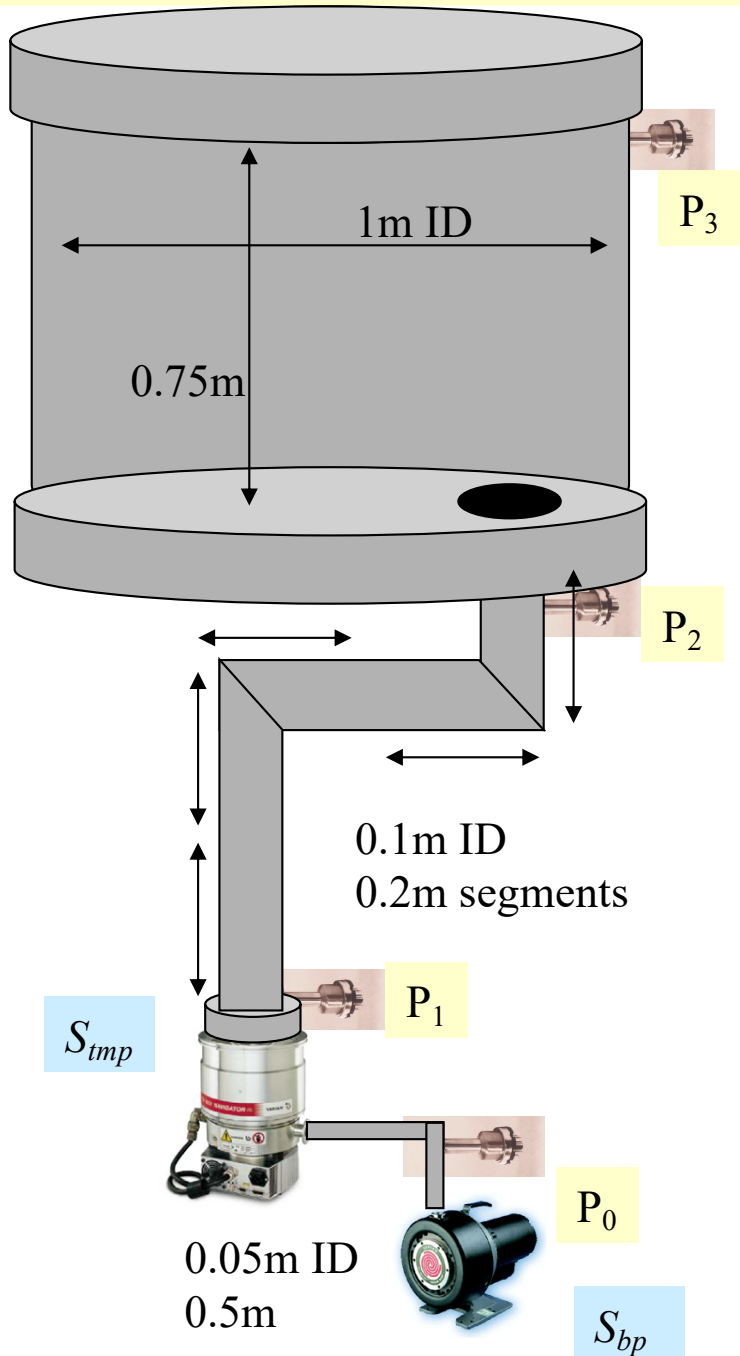
$$C = 0.113 * 11.6 \text{ A l/s-cm}^2, A = \pi (5)^2$$

$$C = 0.113 * 911. \text{ l/s} = 103 \text{ l/s}$$

O' Hanlon, 3<sup>rd</sup> Ed. Figs. 3.4 & 3.10



# Vacuum Technology, Simple System –2b–



**Complete system: no leaks!**

SS chamber,  $S_{tmp} = 300$  l/s, ( $S_{bp} = 200$  l/min)

$$P_1 = 2.4 \times 10^{-4} \text{ Pa} \rightarrow 1.8 \times 10^{-6} \text{ torr}$$

Chamber entrance:  $P_2$

$$Q_{off-gas} = C(P_2 - P_1) \rightarrow P_2 = P_1 + \left( \frac{Q_{off-gas}}{C} \right)$$

$$C_{line} \sim 103. \text{ l/s} \quad (C_{aperture} \sim 910 \text{ l/s})$$

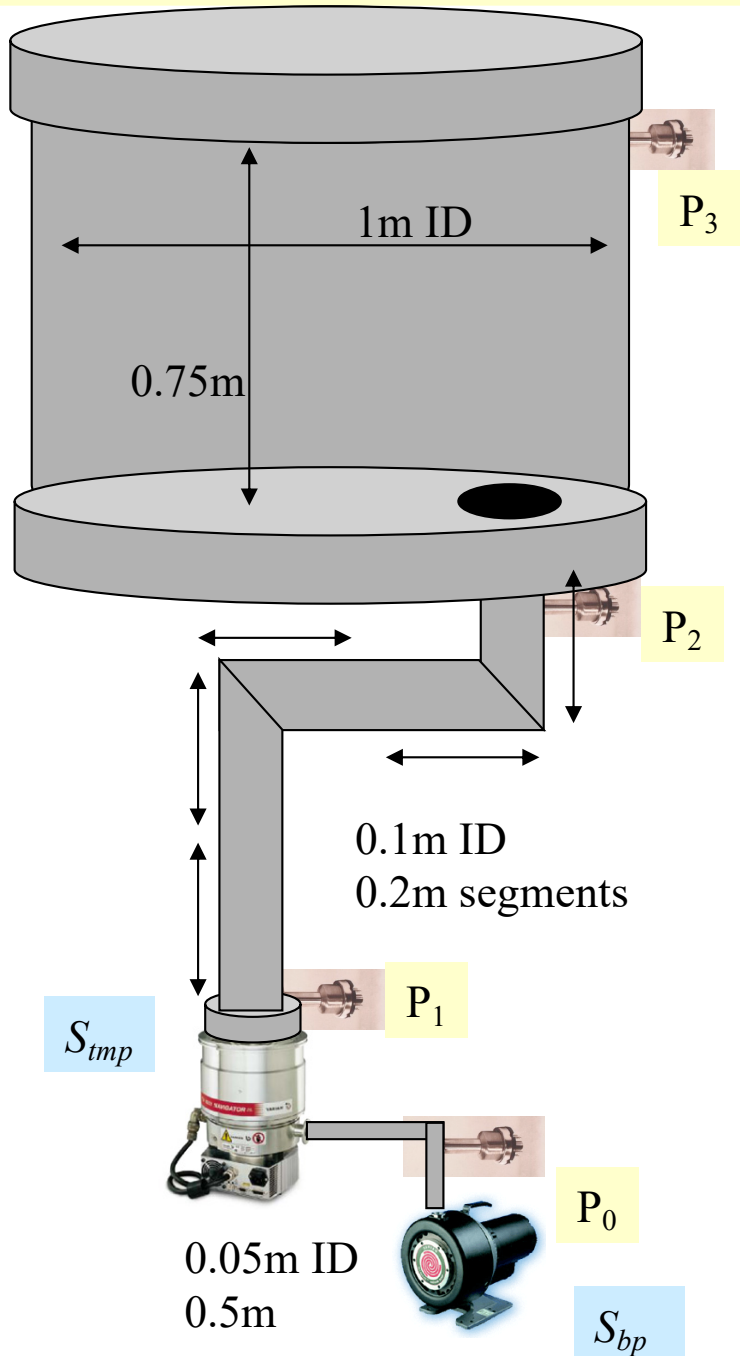
$$P_2 = 2.4 \times 10^{-4} \text{ Pa} + \left( \frac{7 \times 10^{-5} \text{ W}}{0.103 \text{ m}^3 / \text{s}} \right) = 9.2 \times 10^{-4} \text{ Pa}$$

$$P_2 = 6.9 \times 10^{-6} \text{ torr}$$

**Effective Speed:  $S_{eff}$**

$$\frac{1}{S_{eff}} = \frac{1}{C} + \frac{1}{S_{tmp}} \rightarrow \frac{1}{103} + \frac{1}{300} \sim \frac{1}{77}$$

# Vacuum Technology, Simple System –2b–



**Complete system: no leaks!**

SS chamber,  $S_{tmp} = 300$  l/s, ( $S_{bp} = 200$  l/min)

$$P_1 = 2.4 \times 10^{-4} \text{ Pa} \rightarrow 1.8 \times 10^{-6} \text{ torr}$$

Chamber entrance: P<sub>2</sub>

$$Q_{off-gas} = C(P_2 - P_1) \rightarrow P_2 = P_1 + \left( \frac{Q_{off-gas}}{C} \right)$$

$$C_{line} \sim 103. \text{ l/s} \quad (C_{aperture} \sim 910 \text{ l/s})$$

$$P_2 = 2.4 \times 10^{-4} \text{ Pa} + \left( \frac{7 \times 10^{-5} \text{ W}}{0.103 \text{ m}^3 / \text{s}} \right) = 9.2 \times 10^{-4} \text{ Pa}$$

$$P_2 = 6.9 \times 10^{-6} \text{ torr}$$

Chamber top: P<sub>3</sub>

One “pipe” with  $L = 0.75$  m ,  $L/r = 1.5$ ,  $a \sim 0.6$

$$C = 0.6 * 11.6 \text{ A l/s-cm}^2, \quad A = \pi (50)^2$$

$$C = 0.6 * 91,106. \text{ l/s} = 54,663 \text{ l/s}$$

N.B.  $\lambda = 6.6 \text{ mm-Pa/P} \rightarrow 7.1 \text{ m}$



# Vacuum Technology, System Summary

## **Complete system:**

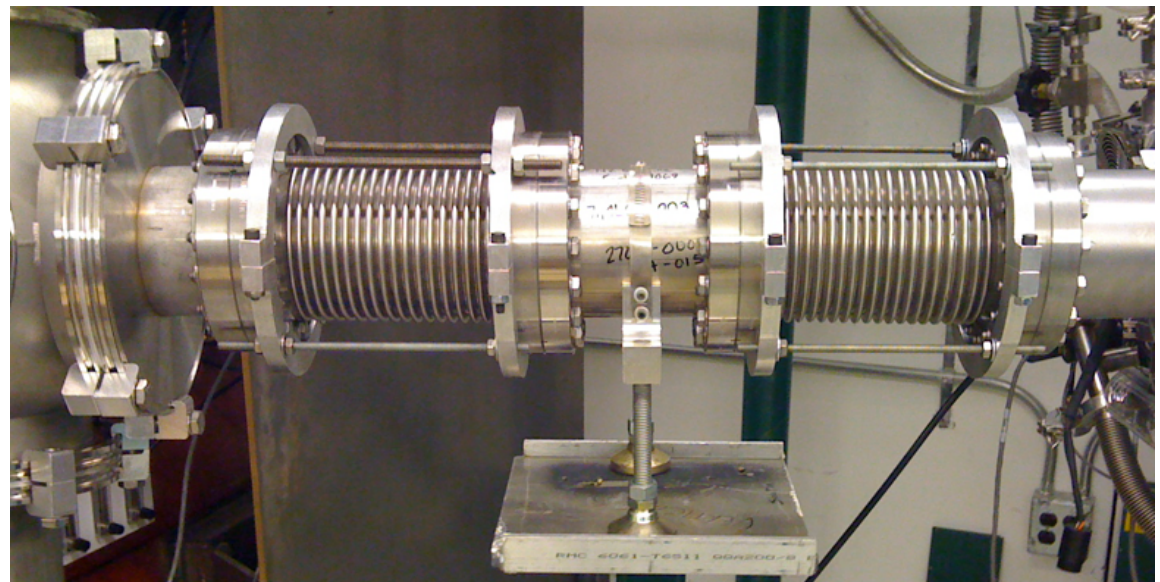
Pumps: speed – depends on the design, gas, and pressure. Is higher pumping speed always the best answer?

Gauges & pressure: measurement principle? – range is limited by technique and is probably the most over interpreted aspect of vacuum technology.

Chamber: materials – unless you are very careful, off-gassing generally determines the lowest pressure the system will attain.

Chamber: seals – better know as “leaks”

Pipes & valves: conductance – limited by size and shape of plumbing, probably the most overlooked concept in vacuum technology.



## Vacuum Technology

### **General use of Statistical Distributions in Radiation Measurements**

- Fluctuations in Number
- distribution function models
- Fluctuations in Time

## General Detector Properties



“Without deviation from the norm, progress is not possible.”  
Frank Zappa, 1986